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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10091588	FILING DATE 03/07/2002	CLASS 217	SUBCLASS 217	GAU 2812	EXAMINER TRAN Kramer
**APPLICANTS: Kimoto Shinyo; Tokunaga Kenji; Kim Seokhyun; Muguruma Terumi; Yamada Yoshiaki; Watanabe Shinichi; Nishi Masahiro; 3652					
**CONTINUING DATA VERIFIED:					
** FOREIGN APPLICATIONS VERIFIED: JAPAN 2001-066041 03/09/2001					
PG-PUB <input type="checkbox"/>		DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>	
Foreign priority claimed		<input type="checkbox"/> yes <input type="checkbox"/> no		ATTORNEY DOCKET NO	
35 USC 119 conditions met		<input type="checkbox"/> yes <input type="checkbox"/> no		025311-0116	
Verified and Acknowledged Examiners's initials					
TITLE : Substrate processing apparatus, substrate processing system, and substrate conveying method					
U.S. DEPT. OF COMM./PAT & TM-PTO-436 (Rev. 12-94)					

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	Print Claim for O.G
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drwg.	Figs. Drwg.
		Print Fig.	
		Applicati n Examiner	
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	
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